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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : Confirmation No. 7391  
Tatsuya SASAKI et al. : Attorney Docket No. 2005\_1908A  
Serial No. 10/559,815 : Group Art Unit 1792  
Filed March 23, 2006 : Examiner Sylvia MacArthur

POLISHING APPARATUS  
AND POLISHING METHOD

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RESPONSE

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEES FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975

Sir:

Pursuant to the requirement contained in the Office Action mailed November 14, 2008,  
Applicants hereby elect invention II, claims 5-8, drawn to a polishing method.

In view of this election, a full examination on the merits of the present application is  
respectfully requested.

Respectfully submitted,

Tatsuya SASAKI et al.

By: David M. Ovedovitz  
David M. Ovedovitz  
Registration No. 45,336  
Attorney for Applicants

DMO/jmj  
Washington, D.C. 20006-1021  
Telephone (202) 721-8200  
Facsimile (202) 721-8250  
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